Form PTO 1449	ATTY. DOCKET NUMBER NITT.0161		C
. U.S. Department of Commerce Patent and Trademurk Office.	APPLICANT Shichi et al		
Information Disclosure Statement by Applicant	False Date Concurrently Herewith	GROUP 2881	

Examiner Initial	Cited by Examiner in	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FEING DATE
	Parent				ŀ		
OME	X	6,039,000	3/21/2000	Libby et al.			2/11/98
ont	X	5,270,552	12/14/93	Ohnishi et al.			8/21/92
cml	X	5,986,264	11/16/99	Grunewald			4/22/96
cmt	X	5,089,774	2/18/92	Nakano	-	 	12/24/90

Examiner Initial	Filed In Parena	DOCUMENT NUMBER	FILING DATE	COUNTRY	Cuss	SVD- CLASS	TRANSLATION	
							YES	No
cour	X	05-052721	8/22/91	Japan			Abstract	X
cme cme	x	WO99/05506	7/21/98	wo			Abstract	X
cme	X	03-166744	11/27/89	Japan			Abstract,	X
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Other Documents (Including Author, Title, Date Pertinent Pages, Etc.) Filed in Parent L.A. Giannuzzi, J.I. Drown, S.R. Brown, R. B. Irwin, F.A. Stevie, "Focused Ion Beam Milling and Micromanipulation Lift-out for Site Specific Cross-Section TEM Specimen Preparation", Material CAL Research Society Symposium Proceeding (1997), Vol. 480, pp. 19-27. L.R. Herlinger, S. Chevacharoenkul, D.C. Erwin, "TEM Sample Preparation Using a Focused Ion Beam X and a Probe Manipulator", Proceedings of the 22nd International Symposium for Testing and Failure OMK Analysis, 18-22 November 1996, pp. 199-205 x "Election and Ion Beam Handbook", Third Edition, (Japan Society for the Promotion of Science, 132 CAR dommission, Nikkan Kogyo ShinbunSha), pp. 458-461 04/23/04 DATE CONSIDERED

EXAMINER: Initial if cliation is considered, whether or not cliation is in conformance with MPEP 609; draw a line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant

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